

# Front-end Electronics for Silicon Trackers readout Deep Sub-Micron Technology

The case of Silicon strips at the ILC

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and

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# Outline

- Context of the Silicon strips for the ILC
- Integrated electronics
- 180nm CMOS chip
- First design in 130nm
- Future plans

# Silicon strips for the ILC

# Silicon strips tracker at the ILC

- a few  $10^6$  Silicon strips
- 10 - 60 cm long
- Thickness: 200–500 $\mu\text{m}$
- Strip pitch 50–200  $\mu\text{m}$
- Single sided, AC coupled

# Readout parameters

- Interstrip capacitance  $> 1 \text{ pF/cm}$   
Strip to substrate capacitance  $> 0.1 \text{ pF/cm}$
- Occupancy defined as % channels hit per BC:  
  
Outer barrel and end caps layers:  $< 1 \%$   
Inner barrel and end caps layers:  $< \text{a few } \%$
- ILC timing:  $1 \text{ ms: } \sim 3\text{-}6000 \text{ trains @ } 150\text{-}300\text{ns / BC}$   
 $100\text{ms in between}$

# Detector data

- **Pulse height:** Cluster centroid to get position resolution to a few  $\mu\text{m}$

Detector pulse sampling

- **Time:** Two scales:

- Coarse 150-300ns BCO tagging

Two shaping time ranges 500 ns and 2  $\mu\text{s}$

- Nanosecond timing for the coordinate along the strip

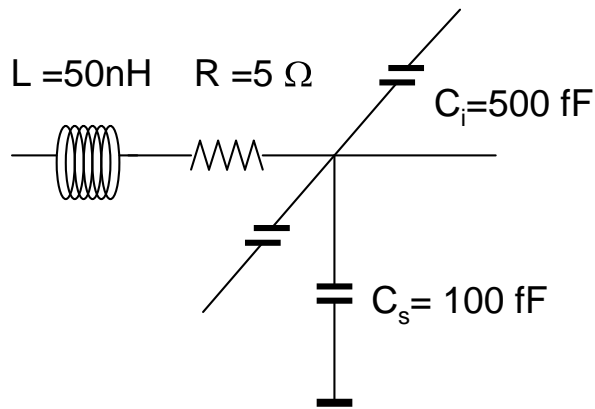
Not to replace another layer or double sided

Spatial estimation to a few cm

Shaping times: 20-100ns

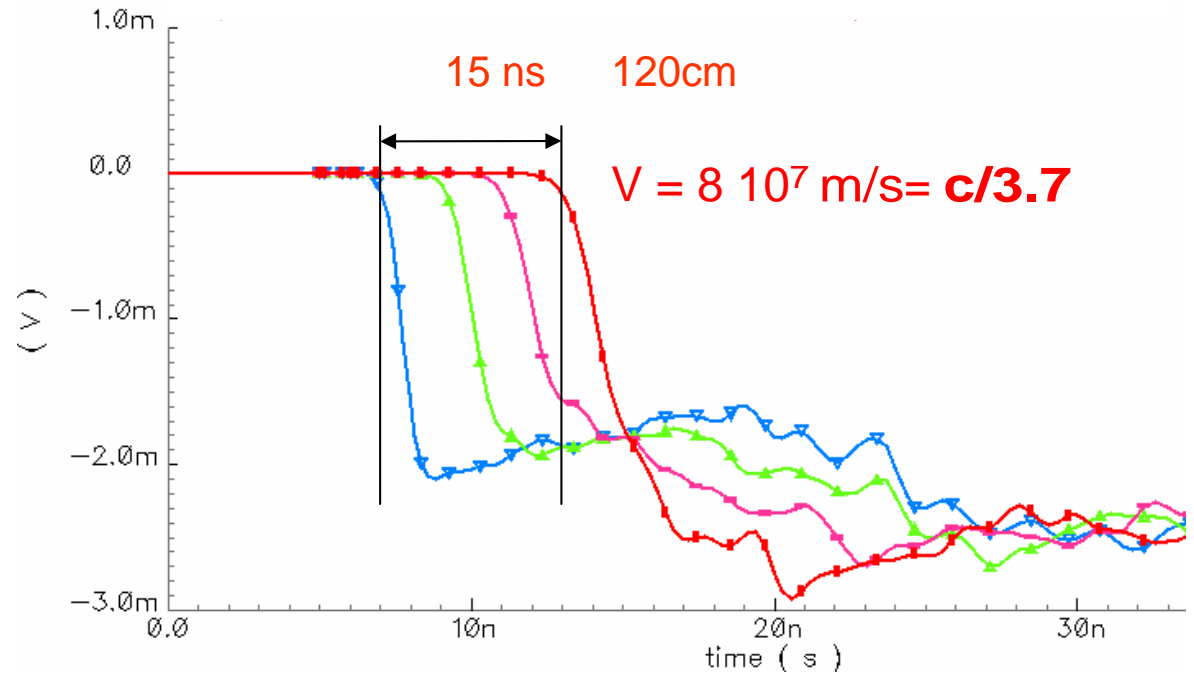
# Coordinate along the strip

SPICE



$$V = 1/\sqrt{LC}$$

$$V = 6.3 \times 10^7 \text{ m/s} = c/4.7$$



**1 ns time resolution is 8 cm**

# Integrated Electronics



# Integrated Electronics

## ● SLAC

### Calorimetry and tracking

Charge: linear 1 or 2-gains, 2500 MIPS

Shaping: reset-sample (2-correlated sampling like)

Time: BC id

## ● UC Santa Cruz

### Tracking

Charge: Time Over Threshold, Lo+Hi thresholds, 128 MIPS

Shaping:  $\mu$ s

Time: BC id

## ● LPNHE Paris

### Tracking

Charge: linear, multiple sampling including pedestal, 50 MIPS

Time: 2-scales

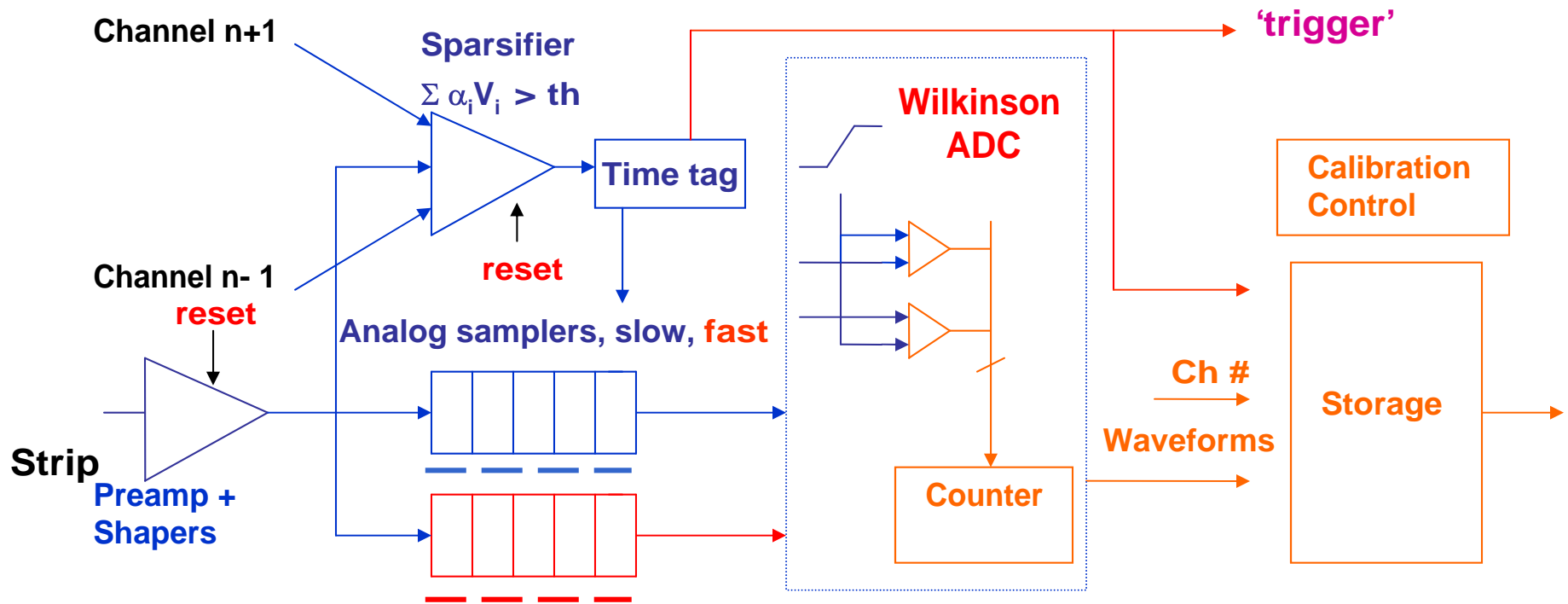
BC id

ns timing (long. coordinate over strips)

# Foreseen on-detector FE chip

- **Pulse sampling:** 16 samples over 2 shaping times (inc pedestal)  
16-deep sampling analog buffer
- **Buffering:** a few 10 events buffer  
2D structure: (a few 10)\* 16 caps/ channel
- **Sparsification/calibration :** On FE chip
- **Analog-Digital conversion:** Wilkinson optimum (power)
- **Digital processing:** Amplitude and time estimation + charge cluster algorithm, lossless data compression
- **Power: 1/100 ILC duty cycle:** FE Power cycling

# Foreseen Front-end architecture



Charge 1- 40 MIP, S/N~ 15- 20, Time resolution: BC tagging, fine: ~ 2ns

Technologies: Deep Sub-Micron CMOS 180-130nm

Future: SiGe &/or deeper DSM

# Charge measurements

- **Preamp + Shaper**
  - Gain: 20mV/MIP over 1-30 MIP
  - S/N = 30 750 e- ENC at 3  $\mu$ s peaking time
  - Reset transistor
- **Analog sampler and event buffer**
  - 2D: 16-deep sampling, a few 10-deep events
- **Sparsifier**
  - Threshold an analog sum of 3 adjacent channels after pulse shaping. Auto-zeroed.
- **ADC**
  - 8-10 bits
  - Clocked at 12 MHz, time interpolated if needed

# Time measurements

- **Time stamping**

BC tagging: resolution of 30 to 50 ns

Time-stamp the sparsifier output at  $4 * \text{BCO clock}$  (83 ns)

- **Fine time measurement**

Order of 1 ns

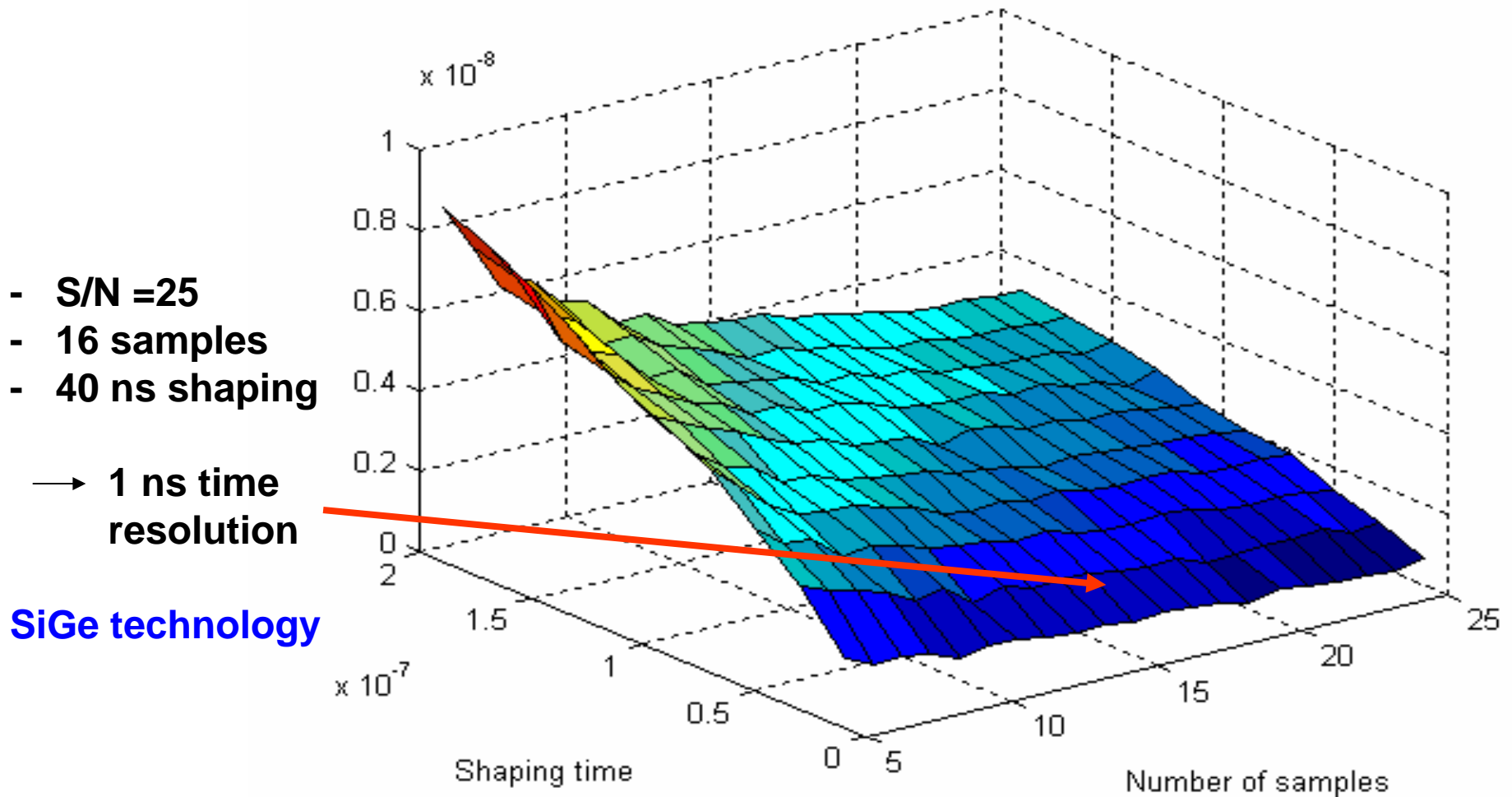
$32 * \text{BCO clock}$  (12ns on-chip vernier sampling clock)

Use digital signal processing over 16 digitized samples

# Expected time resolution

Simulated time resolution using multiple sampling and a least square fit of the shaper pulse algorithm (Bill Cleland)

Time resolution vs Shaping time & Number of samples



# CMOS 180nm Chip

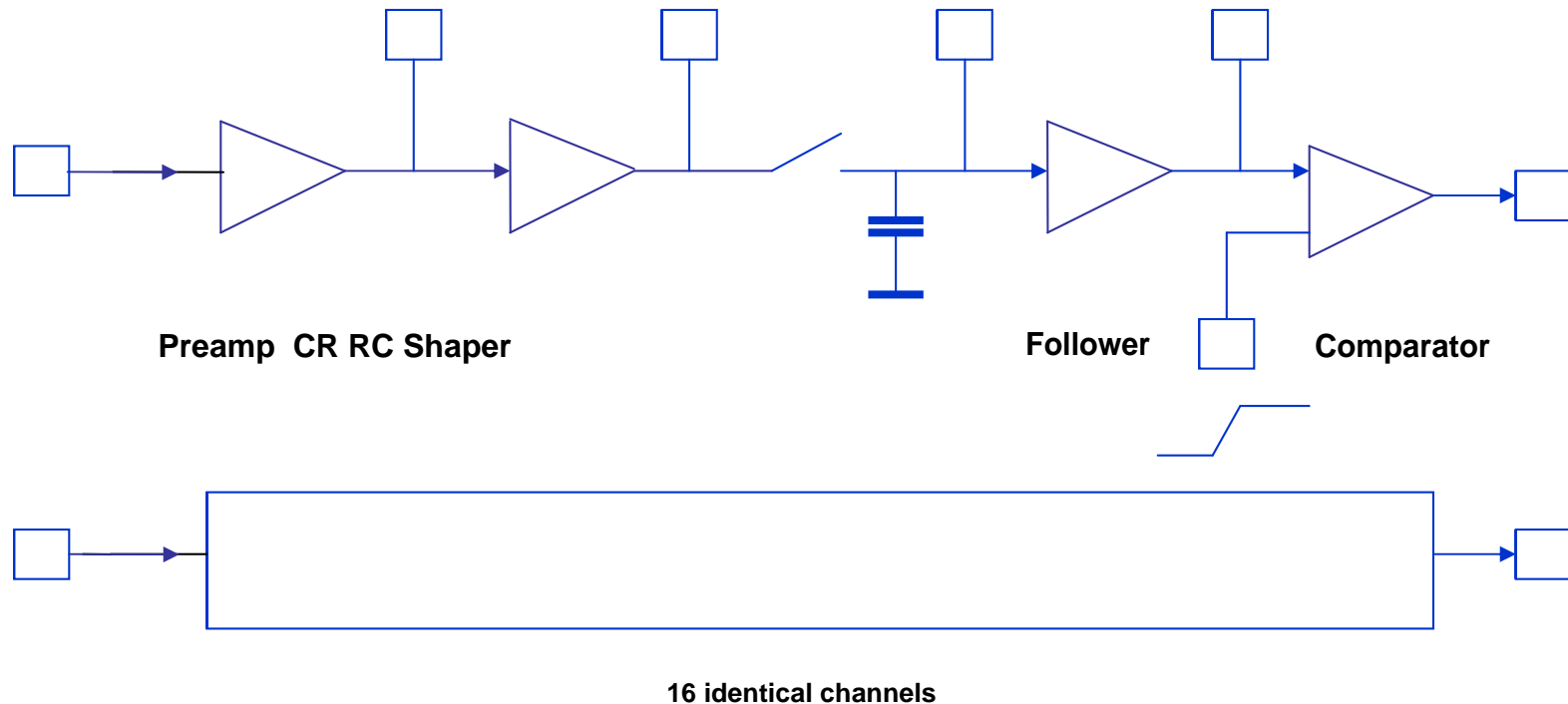
# UMC CMOS 180nm technology

180 nm Mixed-mode process

- 6 metals layers
- 3.3 V transistor
- $C_{ox} = 0.0049 \text{ F/m}^2$
- Metal/Metal capacitance =  $1 \text{ fF/mm}^2$
- Gate's minimum width = 0.5mm
- Various  $V_t$  options



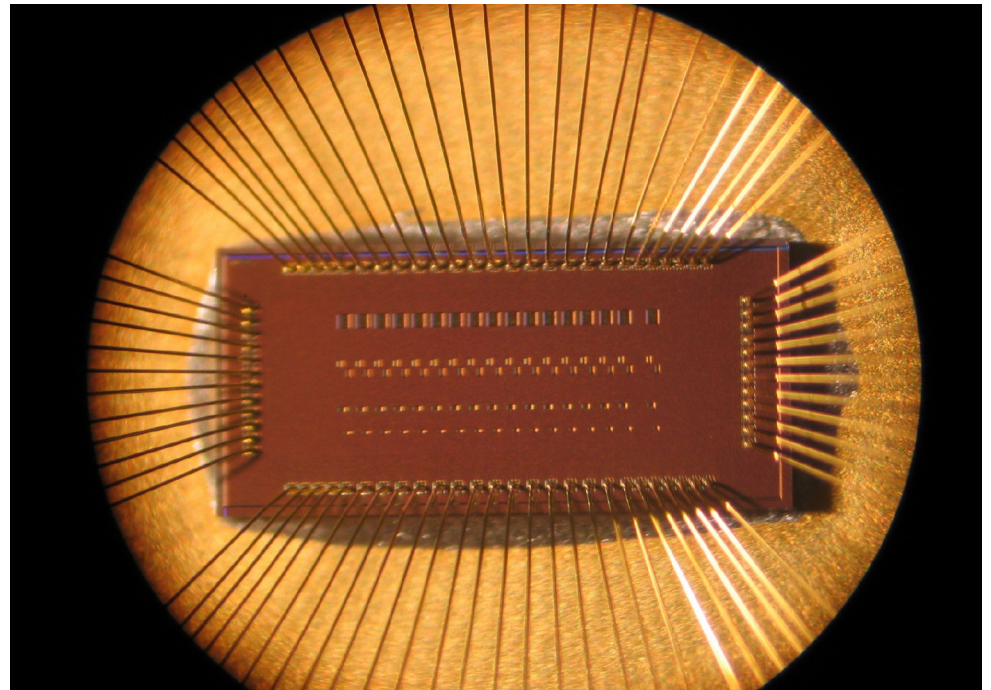
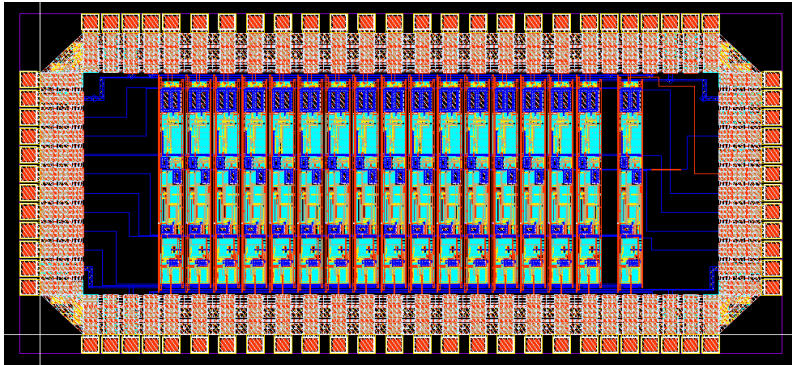
# Front-end test chip in CMOS 180nm



- Low noise amplification + pulse shaping
- Sample & hold
- Comparator

Submitted end '04

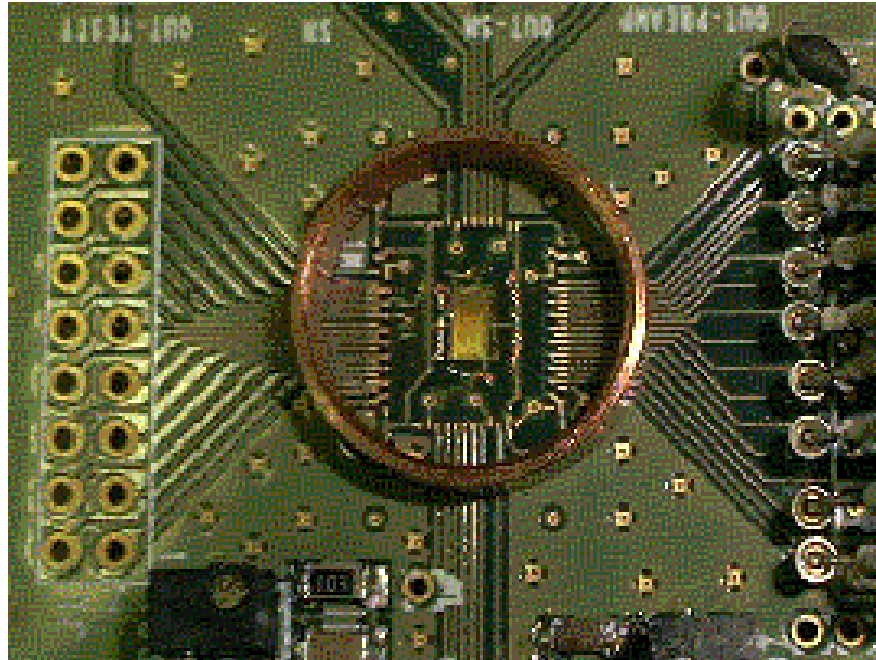
# Silicon



← 3mm →

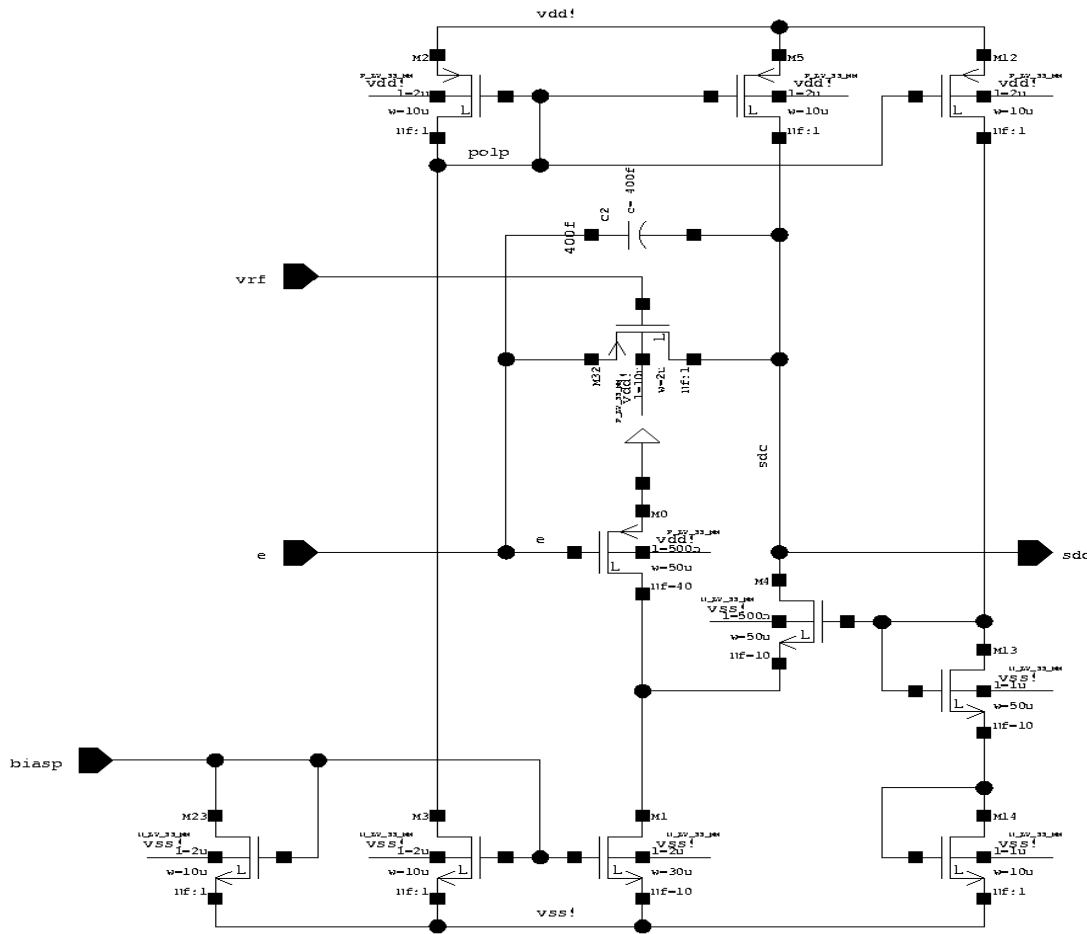
16 + 1 channel UMC 0.18 um chip (layout and picture)

# Test Card

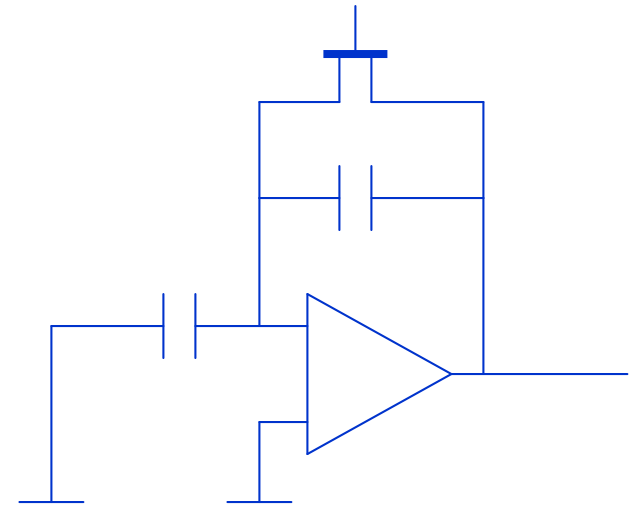


Chip on Board version (wire bonded)

# Preamp



Reset FET



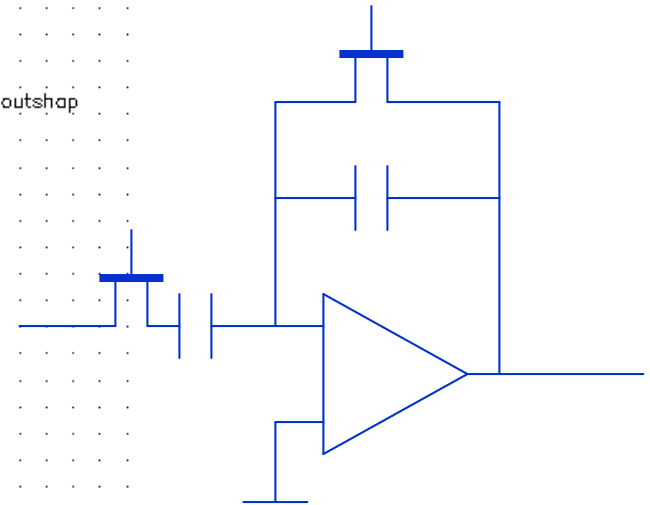
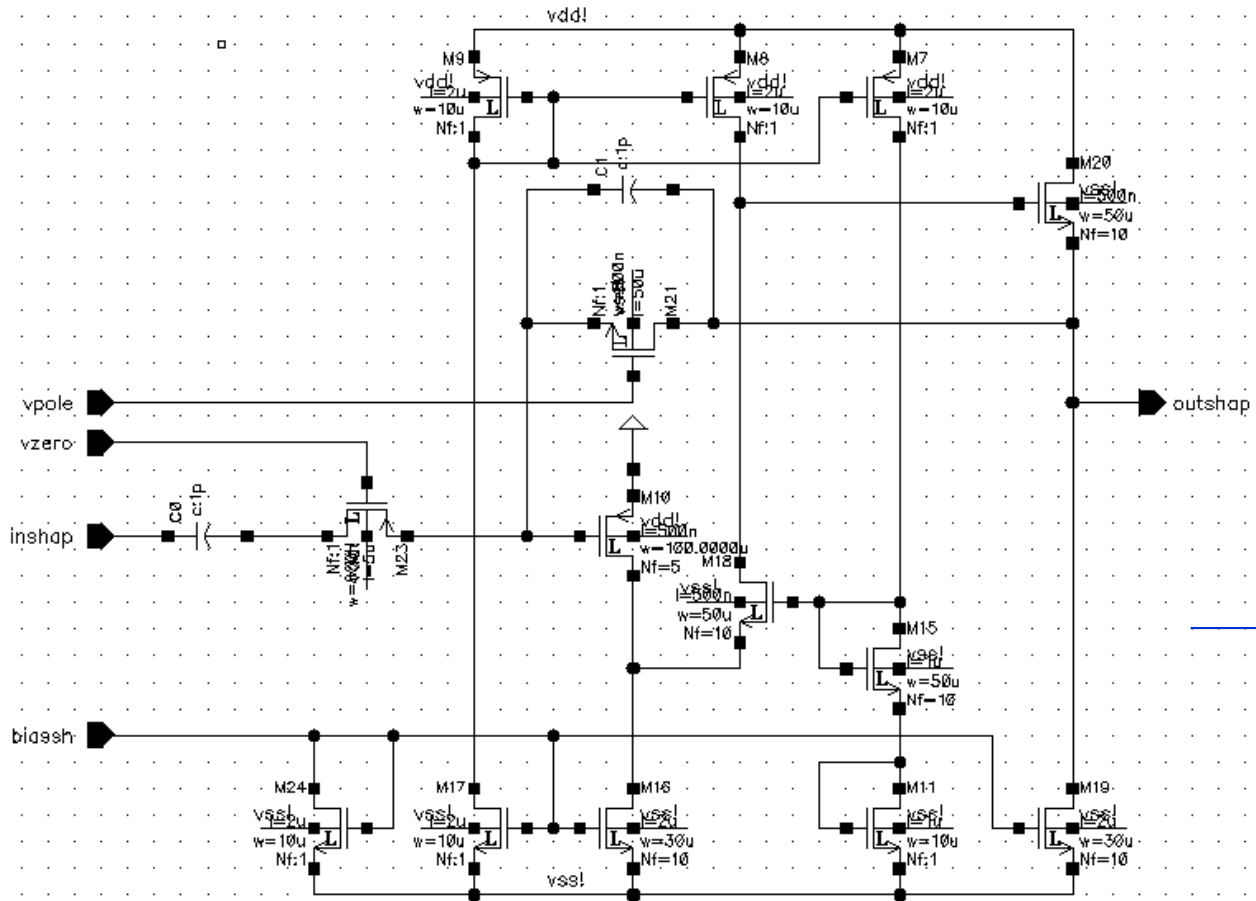
Gain: 8mV/MIP  
 3.3V input transistor 2000/0.5  
 $g_m = 0.69 \text{ mA/V}$   
 40  $\mu\text{A}$  current (Weak inversion  
 $I_C \approx 0.01$ )

# Preamp tests results

Mainly OK

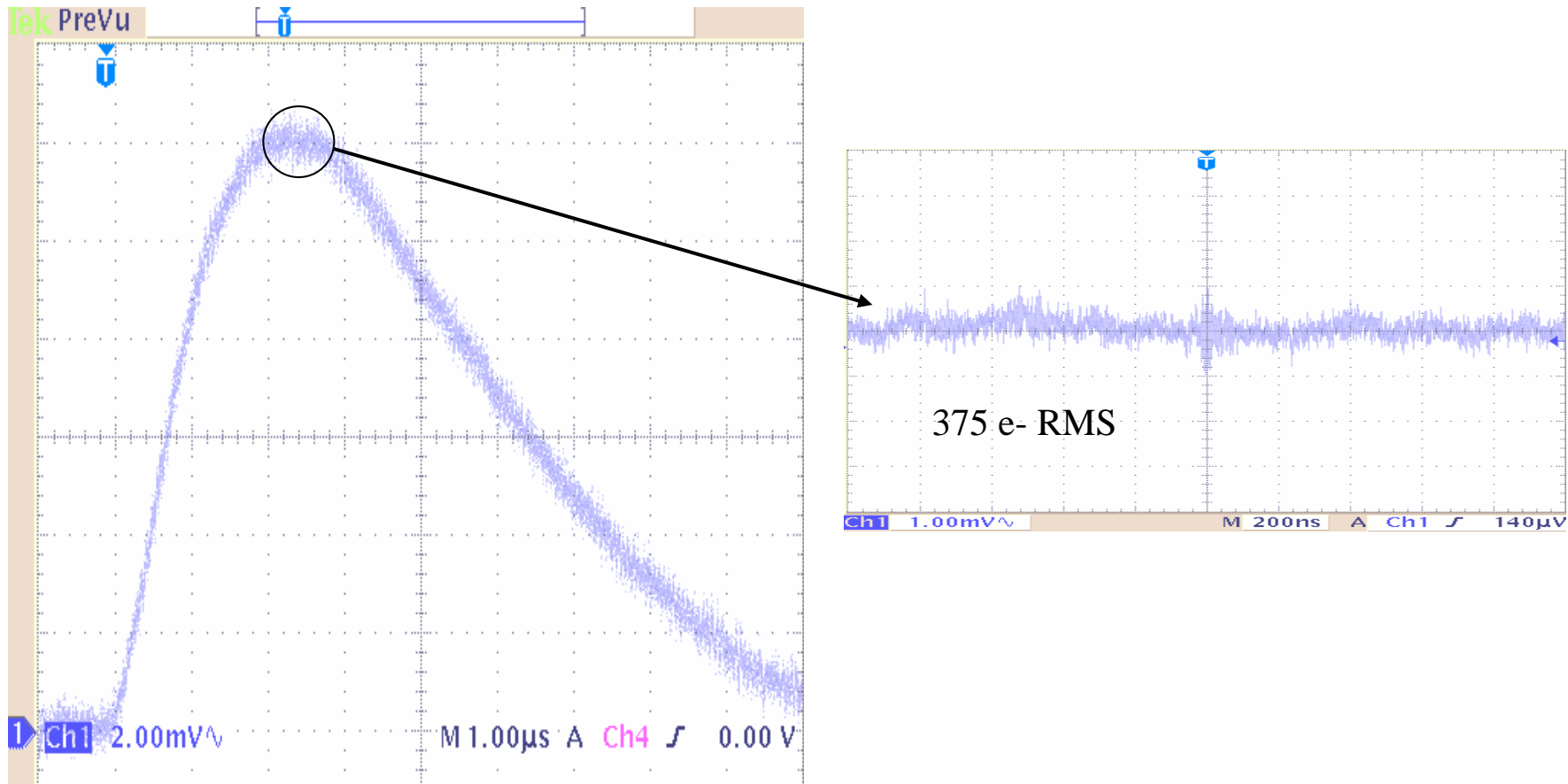
- Gain OK
- Linearity over :  
+/-1.5% +/-0.5% expected
- Noise  $3\mu\text{s}$ - $20\mu\text{s}$  rise-fall times,  $40\ \mu\text{A}$  biasing:  
498 + 16.5 e-/pF OK
- Dynamic range 60 OK

# Shaper



CR-RC 1-5 $\mu$ s

# Shaper Noise



375 e- input noise with chip-on-board wiring (against 280 simulated)

# Shaper tests results

- Peaking time:

1.5 - 6  $\mu$ s tunable peaking time

1-10 targeted

Linearity: +/- 6%

+/- 1% targeted

- Noise @ 3 us shaping time and 140 $\mu$ W power:

375 + 10.4 e-/pF

274 + 8.9 e-/pF expected

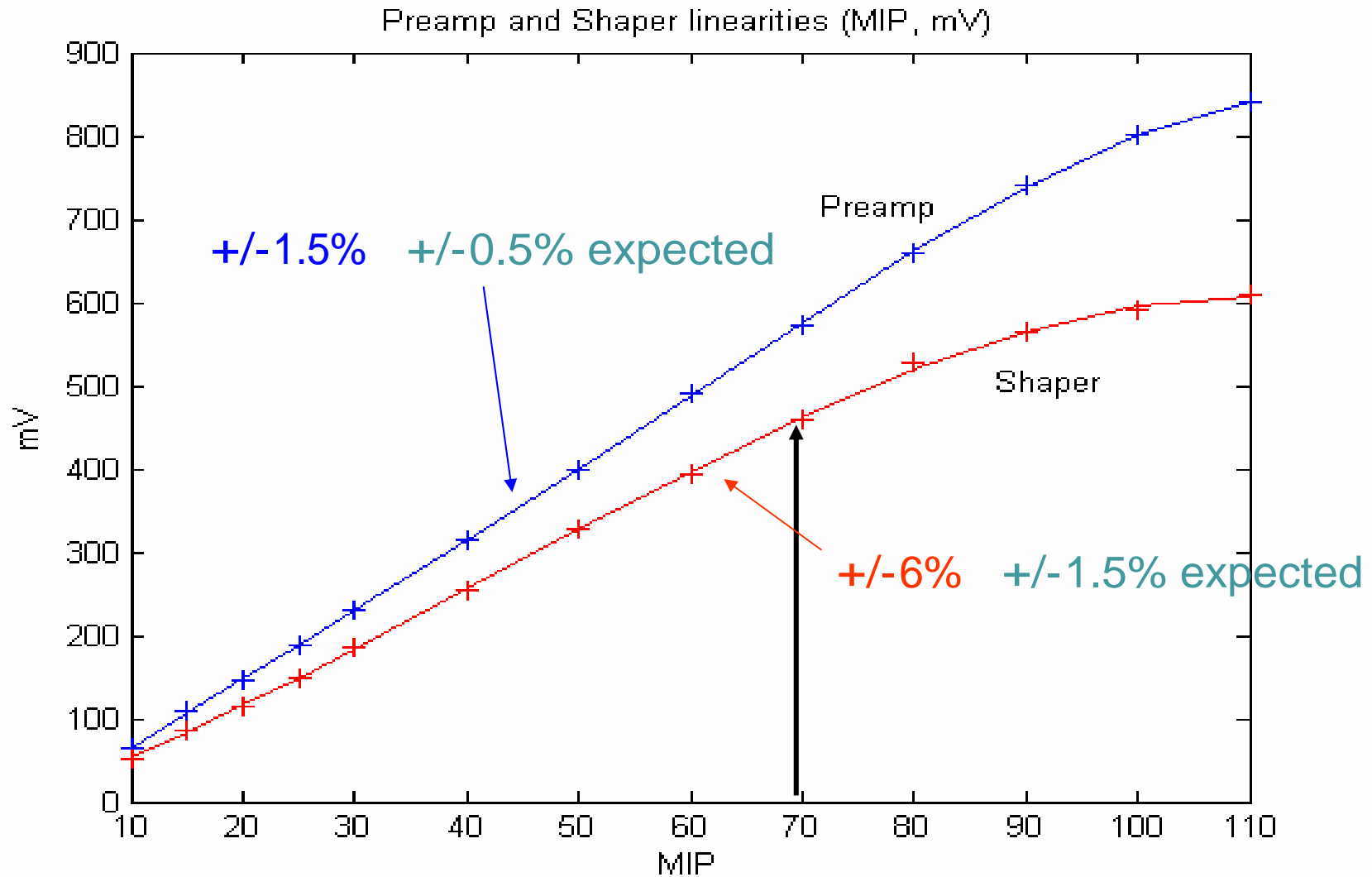
- Linearity:

+/-1.5%

+/-0.5% expected



# Linearities



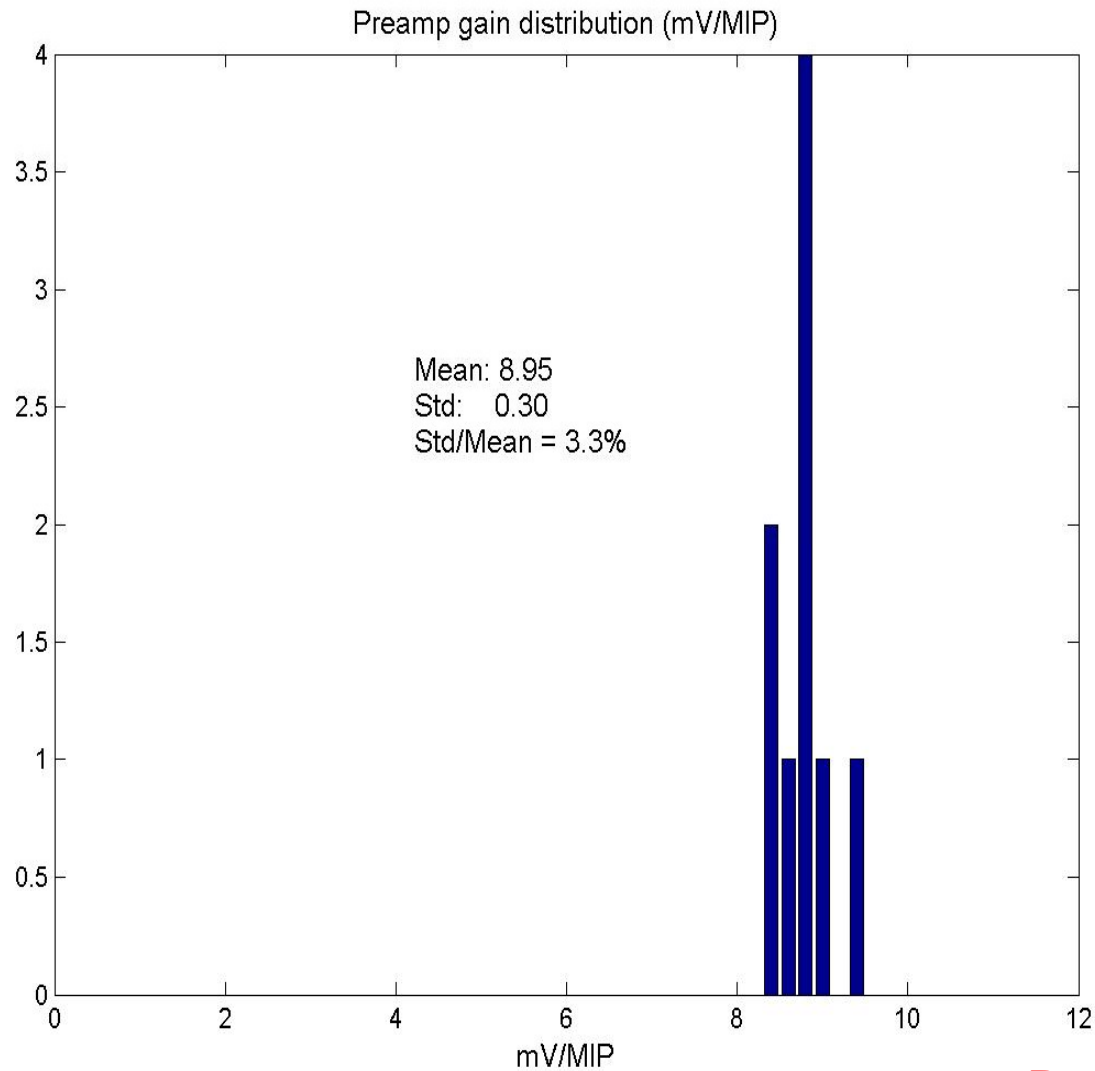
# Sample & Hold Comparator

- Sample and hold: OK
- Comparator:

Vt spreads of the order of 5 mV due to transistors size

- Increase from 10/0.5 to 200/10 to reduce spreads
- Increase Preamp + Shaper voltage gain from 8 to 20 mV/MIP

# Process spreads



Preamp gains statistics

**Process spreads: 3.3 %**

# Tests Conclusions

12 chips tested (June '05)

The UMC CMOS 180nm process is mature and reliable:

- Models mainly OK
- Only one transistor failure over 12 chips
- Process spreads of a few %

Encouraging results regarding CMOS DSM

—————→ go to 130nm

# CMOS 130nm chip design

# Front-end in CMOS 130nm

130nm CMOS:

- Smaller
- Faster
- More radiation tolerant
- Lower power
- Will be (is) dominant in industry

Drawbacks:

- Reduced voltage swing (Electric field constant)
- Leaks (gate/subthreshold channel)
- Models more complex, not always up to date
- Crosstalk (digital)

# Technology parameters

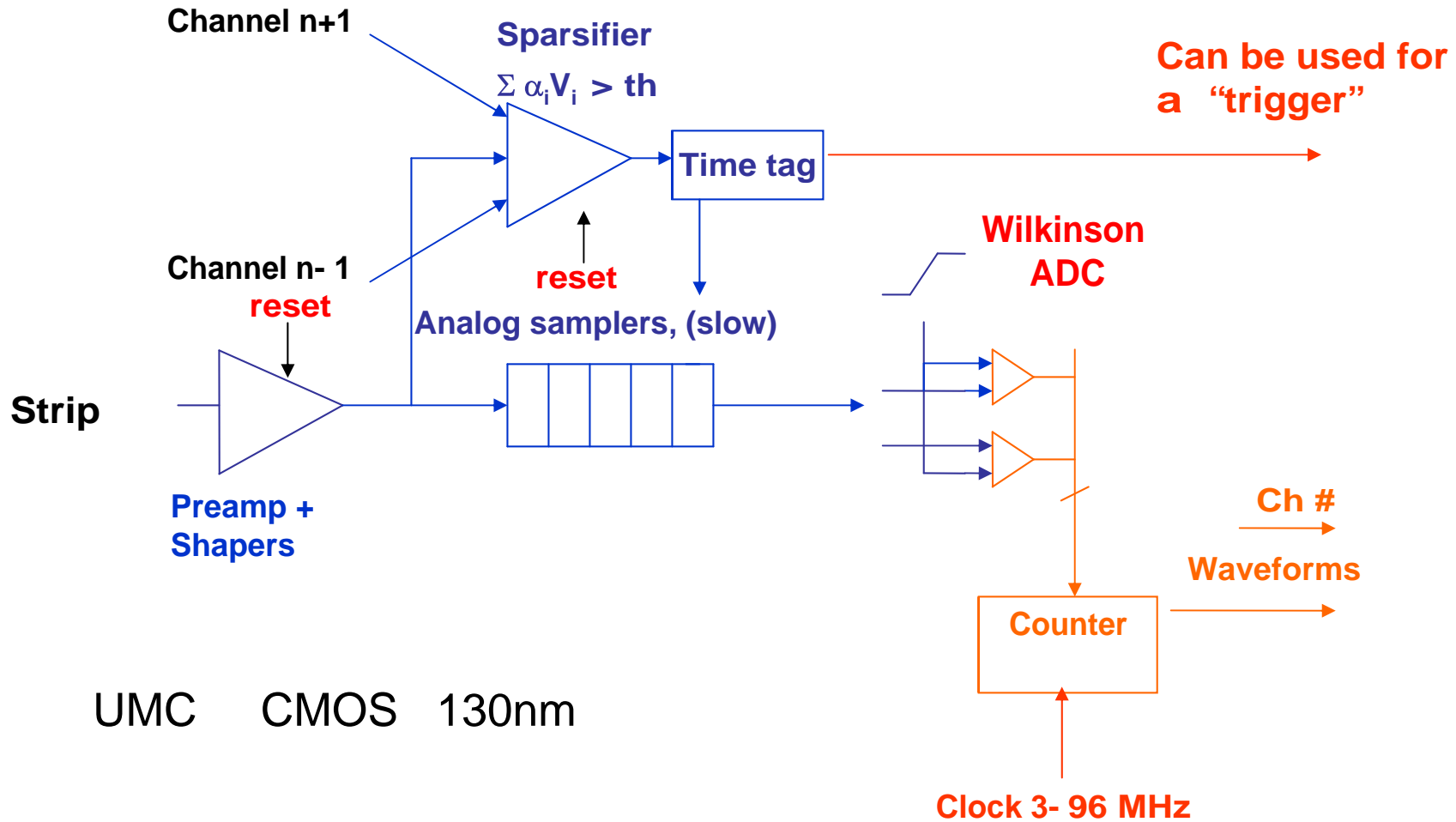
180 nm

- 3.3V transistors
- 1.8V logic supply
- 6 metals layers (Al)
- MIM capacitors =  $1\text{fF}/\mu\text{m}^2$
- Three  $V_t$  options

130nm

- 3.3V transistors
- 1.2V logic supply
- 8 metals layers (Copper)
- MIM capacitors =  $1.5\text{fF}/\mu\text{m}^2$
- Same  $V_t$  options
- Low leakage transistors option

# 4-channel test chip

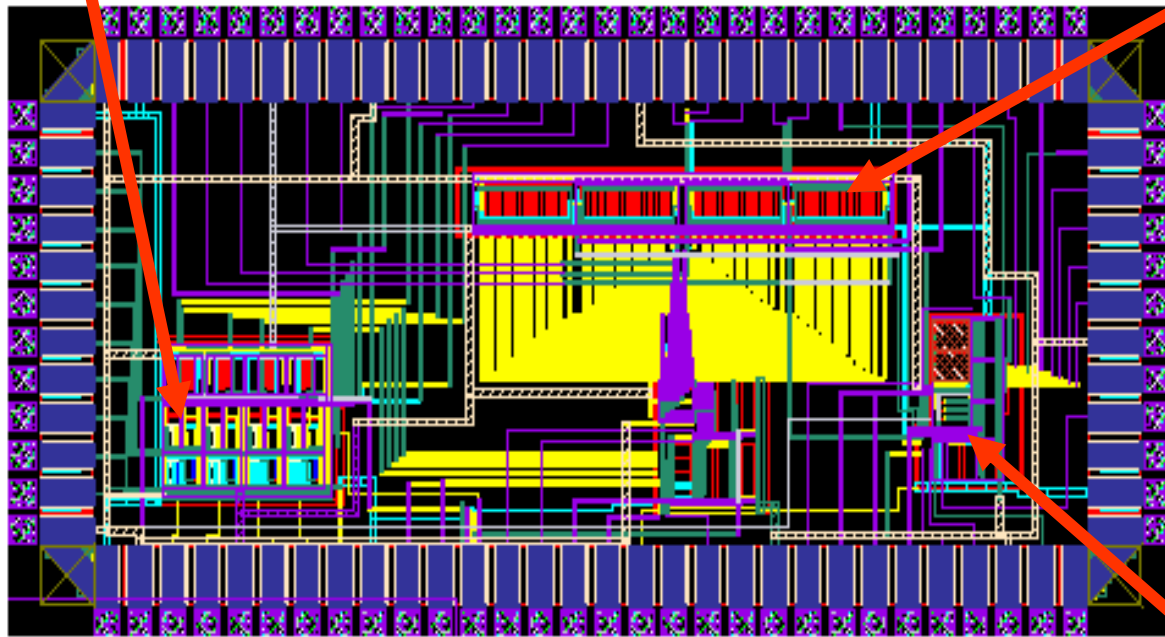




# 130nm CMOS chip

Amplifier, Shaper, Sparsifier 90\*350  $\mu\text{m}^2$

Analog sampler 250\*100  $\mu\text{m}^2$



A/D 90\*200  $\mu\text{m}^2$

Layout of the 130nm chip including sampling and A/D conversion

Submitted April 19<sup>th</sup> '06

# Some issues with 130nm design

- Noise not properly modeled:  
1/f noise out of belief...(both coefficient and exponent)
- Design rules more constraining
- Lower power supplies voltages  
Low  $V_t$  transistors leaky
- Some (via densities) not available under Cadence (Mentor)

# Front-End Digital

- Chip control
- Buffer memory
- Processing for
  - Calibrations
  - Amplitude and time least squares estimation, centroids
  - Raw data after zero suppression lossless compression
- Tools
  - Digital libraries in 130nm CMOS available
  - Synthesis from VHDL/ Verilog
  - SRAM memory
  - PLLs

# Future plans

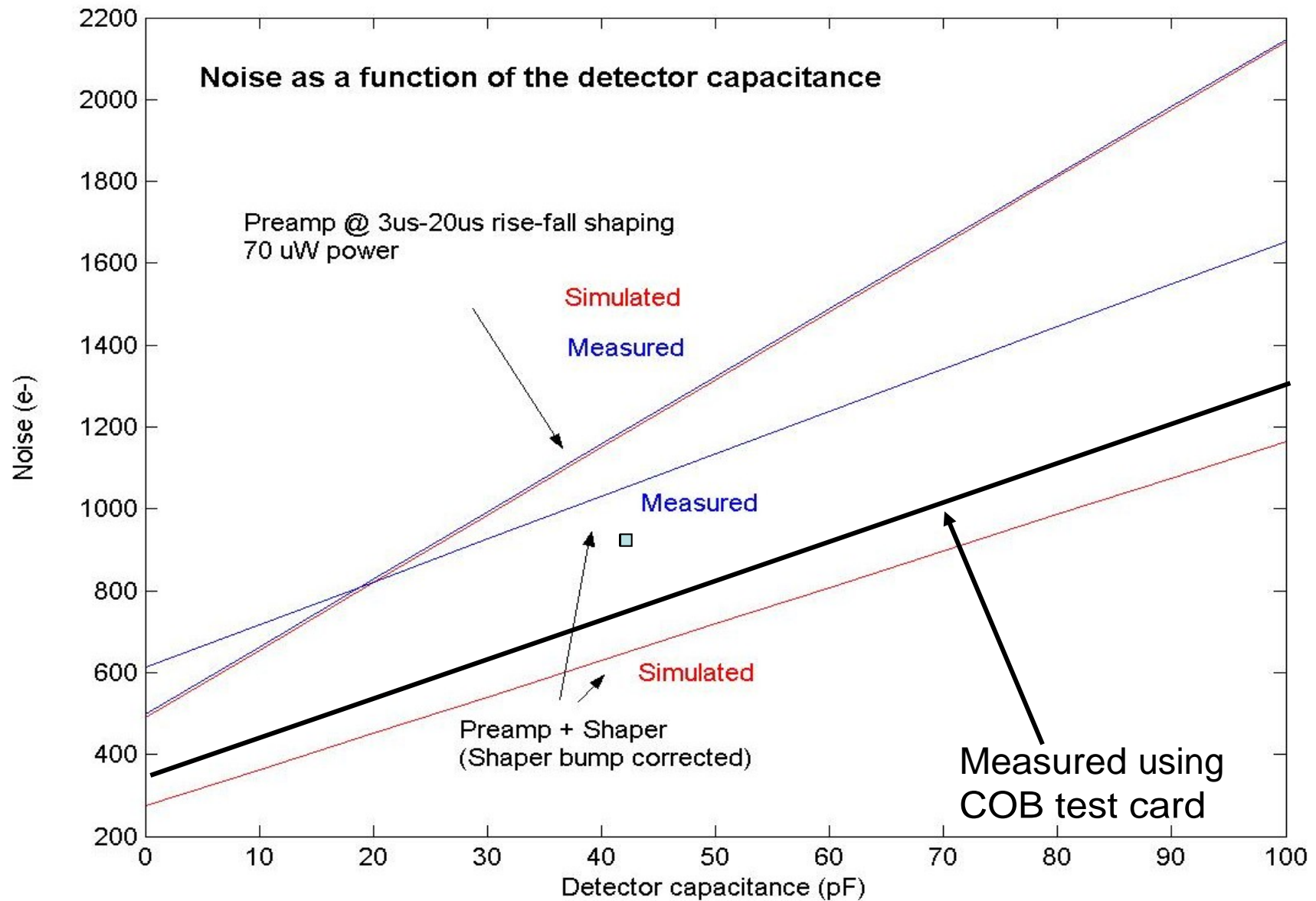
# Future plans

- Implement the fast (20-100ns shaping) version with Silicon-Germanium / CMOS including:
  - Preamp + Shaper (20-100ns)
  - Fast sampling
  - Power cycling
- Submit a full 128 channel version including slow and fast analog processing, power cycling, digital

*The End ...*

Backup

# Noise summary

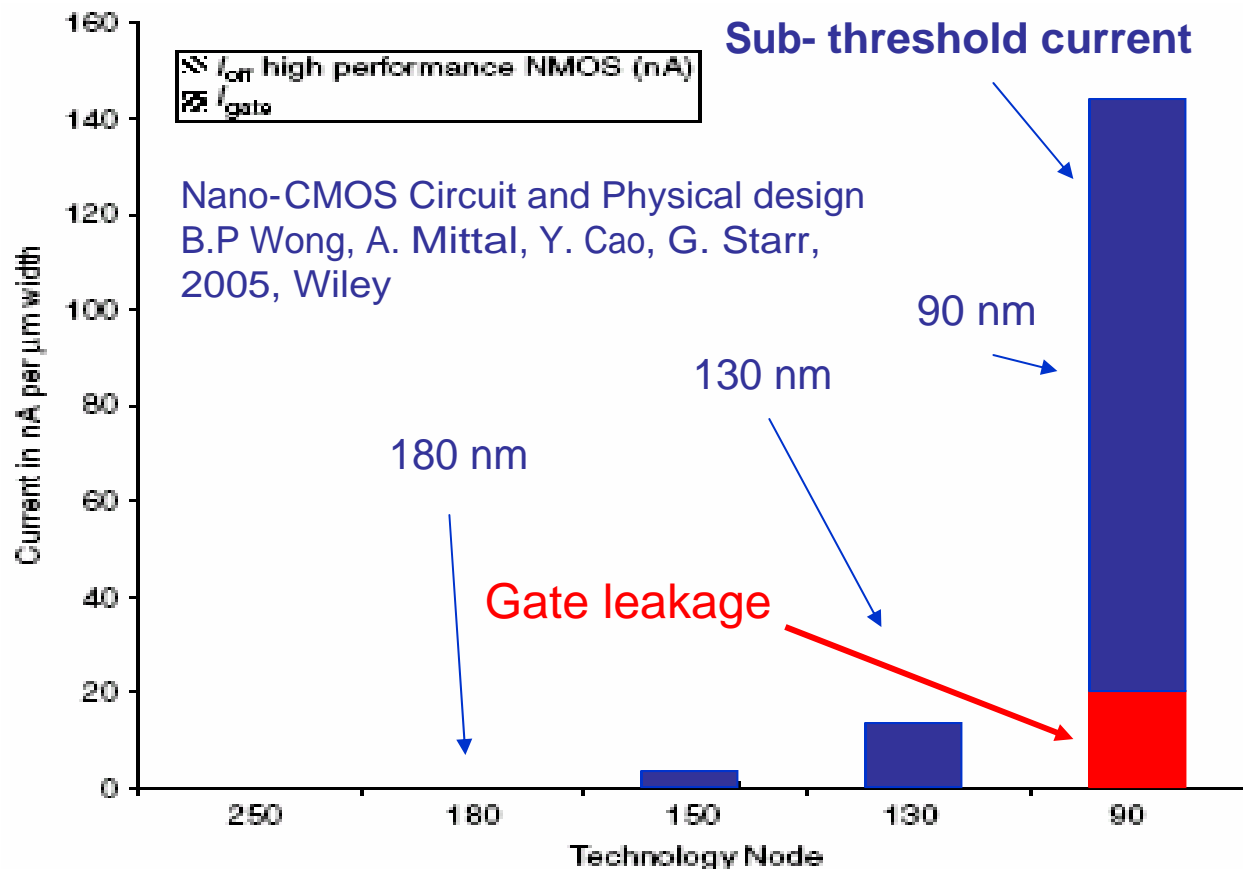




# Possible issues: Transistors leaks

## Two situations:

- Gate-channel due to tunnel effect (can affect noise performances)
- Through channel when transistor switched-off (only affects large digital designs)



- 180nm chip OK
- 130nm, no gate leakage expected, but sub-threshold
- 90nm, important gate leakage

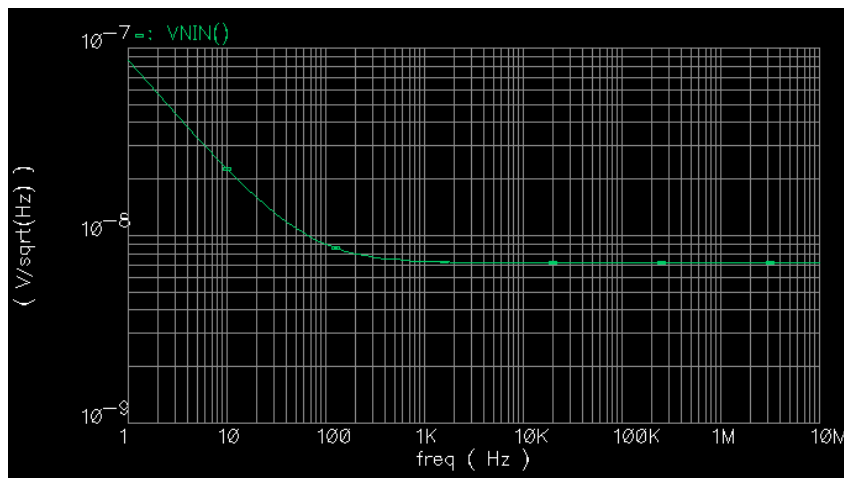
Scale:

1 nA/ $\mu\text{m}$  = 8000 e<sup>-</sup> noise in FE

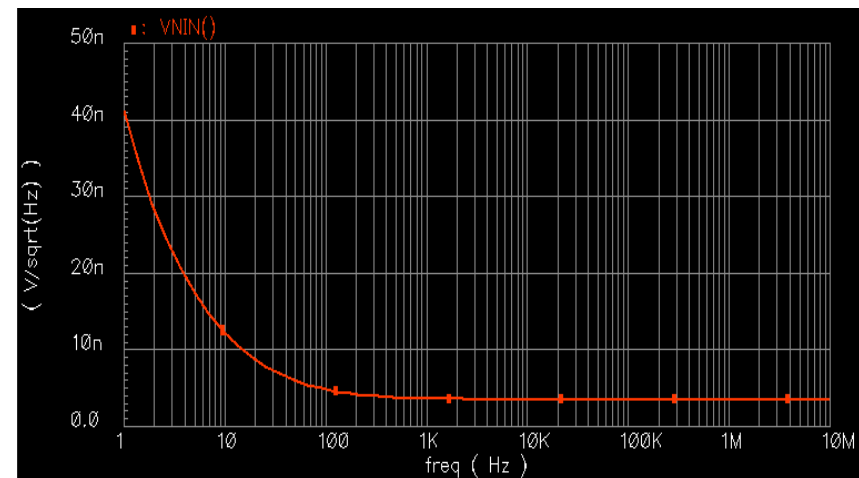
Figure 1.2  $I_{\text{gate}}$  and subthreshold leakage versus technology.

# Possible issues: noise: 130nm vs 180nm (simulation)

## PMOS:



130nm  
 W/L = 2mm/0.5u  
 $I_{ds} = 38.79\mu$ ,  $V_{gs} = -190\text{mV}$ ,  $V_{ds} = -600\text{mV}$   
 $g_m = 815.245\mu$ ,  $g_{ms} = 354.118\mu$   
**1MHz  $\rightarrow$  7.16nV/sqrt(Hz)**  
 Thermal noise hand calculation = 3.68nV/sqrt(Hz)

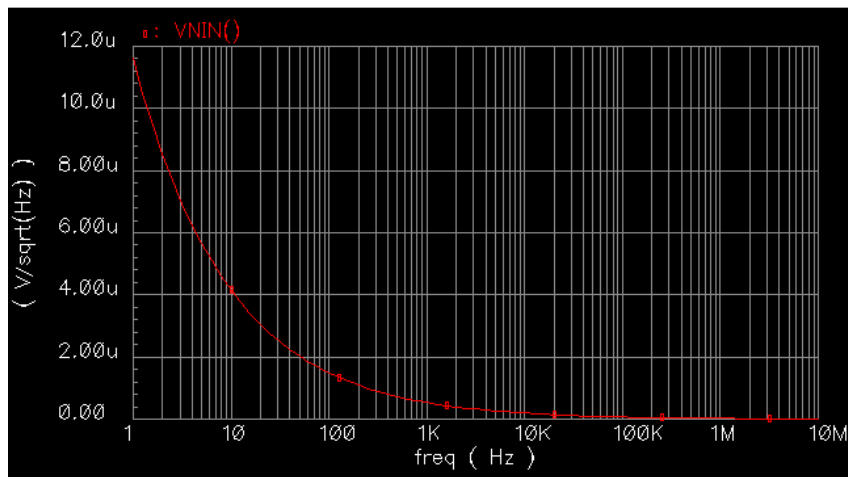


180nm  
 $g_m = 944.4\mu\text{S}$ ,  $g_{ms} = 203.1\mu\text{S}$   
**1MHz  $\rightarrow$  3.508nV/sqrt(Hz)**  
 Thermal noise hand calculation = 3.42nV/sqrt(Hz)

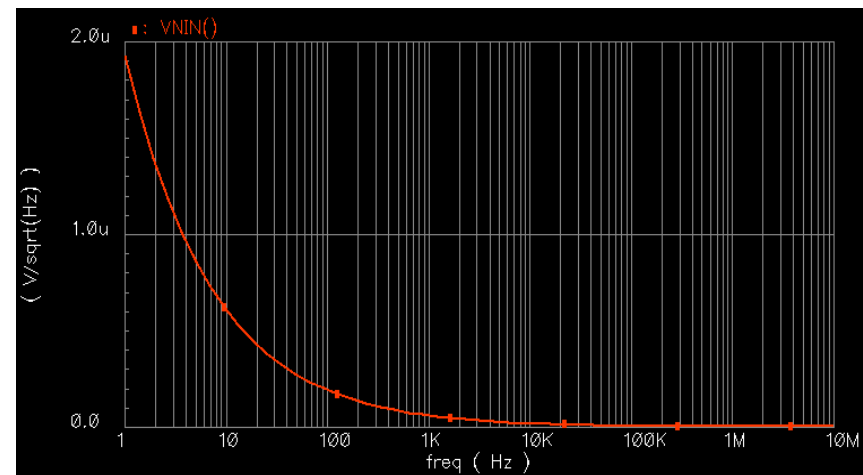
# Noise: 130nm vs 180nm (simulation)



NMOS :



130nm  
W/L = 50u/0.5u  
Ids=48.0505u, Vgs=260mV, Vds=1.2V  
gm=772.031uS, gms=245.341uS, gds=6.3575uS  
**1MHz --> 24.65nV/sqrt(Hz)**  
100MHz --> 5nV/sqrt(Hz)  
Thermal noise hand calculation = 3.78nV/sqrt(Hz)



180nm  
W/L=50u/0.5u  
Ids=47uA, Vgs=300mV, Vds=1.2V  
gm=842.8uS, gms=141.2uS, gds=16.05uS  
**1MHz --> 4nV/sqrt(Hz)**  
10MHz --> 3.49nV/sqrt(Hz)  
Thermal noise hand calculation = 3.62nV/sqrt(Hz)

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